Notice of References Cited Application/Control No. O9/806,224 Examiner George Fourson Applicant(s)/Patent Under Reexamination GRUTZEDIEK ET AL. Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-5,292,671	03-1994	Odanaka, Shinji	438/433
	В	US-5,821,145	10-1998	Goo, Jung-Suk	438/294
	С	US-5,858,828	01-1999	Seliskar et al.	438/234
	D	US-			
	Ε	US-			
	F	US-			
	G	US-			
	Н	US-			
	1	US-			
	J	US-			
	К	US-	_		
	L	US-			
	М	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
:	Z					
	0					
	Р					
	Q					
	R					
	s					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Cheung, NW., "Buried Dopant and Defect Layers for Device Structures With High-Energy Ion Implantation", Nuclear Instreuments and Methods in Physics Research B37/38 (1989) pp.941-950
	٧	
	w	
	х	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.